

Remarks/Arguments:

Applicants acknowledge, with thanks, the courtesy of the Examiner for granting a telephone interview on December 11, 2008.

Claims 1-9 are pending in the above-identified application.

Claims 1, 4 and 8 were rejected under 35 U.S.C. § 103 (a) as being unpatentable over Applicants' admitted prior art in view of Sakakibara et al. It is respectfully submitted, however, that the claims are now patentable over the art of record for the reasons set forth below.

Applicants' invention, as recited by claim 1, includes features which are neither disclosed nor suggested by the art of record, namely:

... spraying a deposition material onto said plasma display panel
from below the substrate;

and permitting an additional amount of said deposition material
to flow through said opening from below the substrate.

Basis for these amendments may be found in the originally filed application at page 19, lines 1 to 5, lines 7 to 10 and Figs. 5A and 5B. No new matter has been added.

The substrate holder 1 in Applicants' exemplary embodiment includes a plurality of frames 2 (center frames) holding substrate 13. That is, the substrate holder includes "...a first frame for holding a substrate of the plasma display panel," as recited in claim 1. The substrate holder 1 in Applicants' exemplary embodiment also includes a plurality of frames 2 (outside frames) having openings 4. (Figs. 3(a) and 3(b)). That is, the substrate holder includes "... a second frame having an opening," as recited in claim 1.

As the substrate holder 1 passes over vapor deposition source 38a, generated vapors 38e (deposition materials) are sprayed from below substrate 13 and deposited on the surface of substrate 13 to form layer 18. (Page 9, line 15 to page 10, line 1 and Fig. 2). Thus, claim 1 has been amended to recite "... spraying a deposition material onto said plasma display panel from below the substrate. Because the substrate holder includes openings 4, an additional amount of vapors pass through openings 4 from below substrate

13. Thus, claim 1 has been amended to recite "... permitting an additional amount of said deposition material to flow through said opening from below the substrate."

The Office Action states that Applicants' admitted prior art teaches providing a substrate holder having first and second frames and providing a plasma display panel which is held by the substrate holder. (Page 3, line 18 to page 3, line 6).

The Office Action then cites to Sakakibara et al. for its teaching of a protrusion which extends higher than the substrate to provide a cover plate 14 to prevent desired impurities from reaching the substrate. (Page 4, lines 7-13).

The cover plate 14 in Sakakibara et al., however, is disposed between the substrate 2 and a radiant heat source 13 above the substrate 2 to prevent undesired impurities ejected from the radiant heat source above the substrate 2. That is, the cover plate member 14 in Sakakibara et al. is for preventing undesired impurities ejected from above the substrate, and not for preventing undesired impurities resulting from "... spraying a deposition material onto said plasma display panel from below the substrate," as recited in claim 1. In fact, Sakakibara et al. does not disclose any material being sprayed from below the substrate and therefore, does not disclose permitting an additional amount of said deposition material to flow through said opening from below the substrate.

Because Sakakibara et al. prevents undesired impurities ejected from above the substrate, and not from below, Sakakibara et al. cannot be combined with Applicants' admitted prior art to disclose "... spraying a deposition material onto said plasma display panel from below the substrate" and "... permitting an additional amount of said deposition material to flow through said opening from below the substrate," as recited in claim 1. Further, because the cover plate 14 in Sakakibara et al. is disposed between the substrate 2 and a radiant heat source 13 above the substrate 2, Sakakibara et al. teaches away from "... permitting an additional amount of said deposition material to flow through said opening from below the substrate," as recited in claim 1.

Accordingly, neither Applicants' admitted prior art, Sakakibara et al., nor their combination disclose or suggest the features of Applicants' claim 1. Thus, claim 1 is allowable over the art of record.

Claim 4, while not identical to claim 1, includes features similar to those set forth above with regard to claim 1. Thus, claim 4 is also allowable over the art of record for reasons similar to those set forth above with regard to claim 1. Claim 8 depends from claim 1. Accordingly, claim 8 is also allowable over the art of record.

Claims 2 and 5 were rejected under 35 U.S.C. § 103 (a) as being unpatentable over Applicants' admitted prior art in view of Sakakibara et al. and Patadia et al. Claims 2 and 5 are allowable, however, because they depend from allowable claims 1 and 4, respectively.

Claims 3 and 6 were rejected under 35 U.S.C. § 103 (a) as being unpatentable Applicants' admitted prior art in view of Sakakibara et al. and Hiroki et al. Claims 3 and 6 are allowable, however, because they depend from allowable claims 1 and 4, respectively.

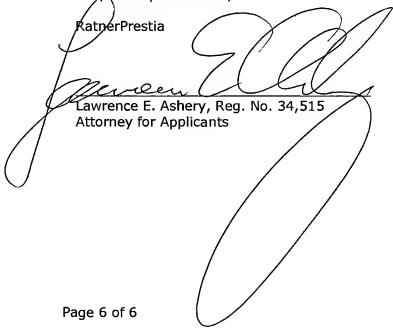
Claim 7 was rejected under 35 U.S.C. § 103 (a) as being unpatentable Applicants' admitted prior art in view of Sakakibara et al. and Won et al. Claim 7 is allowable, however, because it depends from allowable claim 4.

Claim 9 was rejected under 35 U.S.C. § 103 (a) as being unpatentable Applicants' admitted prior art in view of Sakakibara et al. and Yang et al. Claim 9 is allowable, however, because it depends from allowable claim 1.

In view of the foregoing amendments and remarks, this Application is in condition for allowance which action is respectfully requested.

Respectfully submitted,

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